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M. Bauman
2/12/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/783,069 Confirmation No.: 3260
First Named Inventor: Robert J. Small Filing Date: February 13, 2001
Group Art Unit: 2818 Examiner: Thao P. Le
Atty. Docket No.: M-9727 US
Title: Chemical-Mechanical Planarization Using Ozone
Assignee: EKC Technology, Inc.

San Francisco, California
January 31, 2003

COMMISSIONER FOR PATENTS
Washington, D.C. 20231

AMENDMENT

Sir:

This is in response to a non-final office action mailed September 13, 2002 and setting a shortened statutory period for response that expires on December 13, 2002. A petition for a two-month extension of time is submitted herewith. In view of the following amendment and remarks, reconsideration is respectfully requested.

In the Claims:

Please amend Claim 8, such that it reads as set forth below. Please add new Claims 14-26, such that they read, respectively, as set forth below. A marked version of Claim 8 and the new Claims 14-26 are set forth in Appendix I hereto. A clean version of all of the pending claims is set forth in Appendix II hereto.

8. (Amended) A method of planarizing a surface comprising directing ozone gas onto said surface and causing relative motion of said surface and a polishing pad in contact therewith, wherein a fluid is present.

14. (New) A method as in claim 9 wherein the surface comprises a material selected from a group consisting of iridium, iridium oxide, and platinum.

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B1
Sub C1
B2

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